



# Physical Interfaces & Carriers North America TC Chapter

NA Standards Fall Meetings 2019

Wednesday, November 6

SEMI Headquarters, Milpitas, California

10:00–12:00 Noon

## AGENDA

### **1 Welcome/Call to Order**

- 1.1 Introductions
- 1.2 Required Elements (Membership Requirements, Antitrust and Intellectual Property Reminders, and Effective Meeting Guidelines)
- 1.3 Agenda Review

### **2 Review of Previous Meeting Minutes**

### **3 Liaison Report**

- 3.1 Europe TC Chapter – *no update*
- 3.2 Japan TC Chapter

### **4 Staff Report**

### **5 Ballot Review**

None

### **6 Subcommittee & Task Force Reports**

- 6.1 Japan PLP Panel FOUP Task Force
- 6.2 Electron Microscopy (EM) Workflow Task Force
- 6.3 Global PIC Maintenance Task Force



## 7 Old Business

### 7.1 Standards due for Five-Year Review

- SEMI E83-0515, Specification for PGV Mechanical Docking Flange

## 8 New Business

### 8.1 New SNARF(s)

### 8.2 Leadership Change(s)

## 9 Action Item Review

### 9.1 Open Action Items

| <i>Item #</i> | <i>Assigned to</i> | <i>Details</i>                                                                                                  |
|---------------|--------------------|-----------------------------------------------------------------------------------------------------------------|
| 2019July#01   | Laura Nguyen       | To clarify footnote in Style Manual with SEMI.                                                                  |
| 2017April#04  | Laura Nguyen       | To identify which documents under the global task force belong to which committees.<br><a href="#">Ongoing.</a> |

### 9.2 New Action Items

## 10 Next Meeting and Adjournment

10.1 The next meeting is scheduled for Monday, March 30, in conjunction with the NA Standards Spring 2020 Meetings at SEMI Headquarters in Milpitas, California.

### Tentative Schedule:

Tuesday, March 31

13:00-15:00 Electron Microscopy (EM) Workflow TF

15:00-17:00 Japan PLP Panel FOUP TF

Wednesday, April 1

? 09:30–10:00 Global PIC Maintenance TF

10:00-12:00 PIC (C)

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